

The listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

forming a plurality of pixel electrodes arranged in a matrix form over a substrate;

preparing an evaporation cell filled with an organic electroluminescence material; and

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a pattern of a light emitting layer comprising the organic electroluminescence material ~~over a substrate over one selected from the plurality of pixel electrodes without using a mask,~~

wherein the evaporation cell comprises a first portion and a second portion having a diameter smaller than that of the first portion, and

wherein the organic electroluminescence material is ejected from an end portion of the second portion.

2. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

forming a plurality of pixel electrodes arranged in a matrix form over a substrate;

placing in a reaction chamber an evaporation cell containing an organic electroluminescence material and placing a shutter above the evaporation cell;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a pattern of a light emitting layer comprising the organic electroluminescence material ~~over a substrate~~

over one selected from the plurality of pixel electrodes without using a mask by opening and closing the shutter,

wherein the evaporation cell comprises a first portion and a second portion having a diameter smaller than that of the first portion, and

wherein the organic electroluminescence material is ejected from an end portion of the second portion.

3. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

forming a plurality of pixel electrodes arranged in a matrix form over a substrate;

preparing an evaporation cell filled with an organic electroluminescence material; and

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively ~~over a pixel electrode of the light emitting device~~ over one selected from the plurality of pixel electrodes without using a mask,

wherein the evaporation cell comprises a first portion and a second portion having a diameter smaller than that of the first portion, and

wherein the organic electroluminescence material is ejected from an end portion of the second portion.

4. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

forming a plurality of pixel electrodes arranged in a matrix form over a substrate;

placing in a reaction chamber an evaporation cell containing an organic electroluminescence material and placing a shutter above the evaporation cell;

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively ~~over a pixel electrode of the light-emitting device over one selected from the plurality of pixel electrodes without using a mask~~ by opening and closing the shutter,

wherein the evaporation cell comprises a first portion and a second portion having a diameter smaller than that of the first portion, and

wherein the organic electroluminescence material is ejected from an end portion of the second portion.

5. (Original) A method of manufacturing a light-emitting device as claimed in claim 1, wherein more than one evaporation cell is provided.

6. (Original) A method of manufacturing a light-emitting device as claimed in claim 2, wherein more than one evaporation cell is provided.

7. (Original) A method of manufacturing a light-emitting device as claimed in claim 3, wherein more than one evaporation cell is provided.

8. (Original) A method of manufacturing a light-emitting device as claimed in claim 4, wherein more than one evaporation cell is provided.

9. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 1, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

10. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 2, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

11. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 3, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

12. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 4, wherein the light-emitting device is a device selected from the group of: a personal computer, a video camera, a goggle-type display, a digital camera and a cellular phone.

13. (Original) A method of manufacturing a light-emitting device as claimed in claim 1, wherein the organic electroluminescence material is a small molecule material.

14. (Original) A method of manufacturing a light-emitting device as claimed in claim 2, wherein the organic electroluminescence material is a small molecule material.

15. (Original) A method of manufacturing a light-emitting device as claimed in claim 3, wherein the organic electroluminescence material is a small molecule material.

16. (Original) A method of manufacturing a light-emitting device as claimed in claim 4, wherein the organic electroluminescence material is a small molecule material.

17. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 1, wherein the inert gas comprises argon.

18. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 2, wherein the inert gas comprises argon.

19. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 3, wherein the inert gas comprises argon.

20. (Previously Presented) A method of manufacturing a light-emitting device as claimed in claim 4, wherein the inert gas comprises argon.

21. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

forming a plurality of pixel electrodes arranged in a matrix form over a substrate;
preparing an evaporation cell filled with an organic electroluminescence material;
evaporating the organic electroluminescence material in an inert gas atmosphere
at an atmospheric pressure by heating the evaporation cell to form a light emitting layer
comprising the organic electroluminescence material selectively over a pixel electrode
of the light emitting device over one selected from the plurality of pixel electrodes
without using a mask; and

moving the evaporation cell and the substrate relative to each other,

wherein the evaporation cell comprises a first portion and a second portion having a diameter smaller than that of the first portion, and

wherein the organic electroluminescence material is ejected from an end portion of the second portion.

22. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

forming a plurality of pixel electrodes arranged in a matrix form over a substrate;
placing in a reaction chamber an evaporation cell containing an organic electroluminescence material and placing a shutter above the evaporation cell;
evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form a light emitting layer comprising the organic electroluminescence material selectively over a pixel electrode of the light-emitting device over one selected from the plurality of pixel electrodes without using a mask by opening and closing the shutter; and
moving the evaporation cell and the substrate relative to each other,
wherein the evaporation cell comprises a first portion and a second portion having a diameter smaller than that of the first portion, and
wherein the organic electroluminescence material is ejected from an end portion of the second portion.

23. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the evaporation cell is moved.

24. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the evaporation cell is moved.

25. (Previously Presented) A method of manufacturing a light-emitting device according to claim 1, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

26. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

27. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

28. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

29. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

30. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

31. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein a diameter of the second portion is several tens to several hundreds μm .

32. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein a diameter of the second portion is several tens to several hundreds μm .

33. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein a diameter of the second portion is several tens to several hundreds μm .

34. (Previously Presented) The method of manufacturing a light-emitting device according to claim 1 wherein said pattern is directly deposited from said evaporation cell.

35. (Previously Presented) The method of manufacturing a light-emitting device according to claim 2 wherein said pattern is directly deposited from said evaporation cell.

36.-37. (Canceled)

38. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

forming a plurality of pixel electrodes arranged in a matrix form over a substrate;

preparing an evaporation cell filled with an organic electroluminescence material, said evaporation cell adapted to directly deposit a pattern of a light emitting layer comprising the organic electroluminescence material over [[a]] the substrate; and

evaporating the organic electroluminescence material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell to form the pattern of the light emitting layer comprising the organic electroluminescence material over the substrate over one selected from the plurality of pixel electrodes without using a mask,

wherein the evaporation cell comprises a first portion and a second portion having a diameter smaller than that of the first portion, and

wherein the organic electroluminescence material is ejected from an end portion of the second portion.

39. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the evaporation cell is moved.

40. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the evaporation cell comprises a material selected from the group consisting of boron nitride, alumina and tungsten.

41. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein a diameter of the second portion is several tens to several hundreds μm .

42. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein the substrate is moved in X-Y directions.

43. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein the substrate is moved in X-Y directions.

44. (Previously Presented) A method of manufacturing a light-emitting device according to claim 1, wherein the pattern of the light emitting layer has a width of about 50 to 200 μm .

45. (Previously Presented) A method of manufacturing a light-emitting device according to claim 2, wherein the pattern of the light emitting layer has a width of about 50 to 200 μm .

46. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein a pattern of the light emitting layer has a width of about 50 to 200 μ m.

47. (Previously Presented) A method of manufacturing a light-emitting device according to claim 4, wherein a pattern of the light emitting layer has a width of about 50 to 200 μ m.

48. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein a pattern of the light emitting layer has a width of about 50 to 200 μ m.

49. (Previously Presented) A method of manufacturing a light-emitting device according to claim 22, wherein a pattern of the light emitting layer has a width of about 50 to 200 μ m.

50. (Previously Presented) A method of manufacturing a light-emitting device according to claim 38, wherein the pattern of the light emitting layer has a width of about 50 to 200 μ m.

51. (Currently Amended) A method of manufacturing a light-emitting device, comprising the steps of:

forming a plurality of pixel electrodes arranged in a matrix form over a substrate;
preparing an evaporation cell filled with an organic material,
evaporating the organic material in an inert gas atmosphere at an atmospheric pressure by heating the evaporation cell;
forming a pattern comprising the organic material over a substrate over one selected from the plurality of pixel electrodes without using a mask; and

moving the evaporation cell and the substrate relative to each other,
wherein the evaporation cell comprises a first portion and a second portion
having a diameter smaller than that of the first portion, and
wherein the organic electroluminescence material is ejected from an end portion
of the second portion.

52. (Previously Presented) A method of manufacturing a light-emitting device
according to claim 51, wherein more than one evaporation cell is provided.

53. (Previously Presented) A method of manufacturing a light-emitting device
according to claim 51, wherein the light-emitting device is a device selected from the
group of: a personal computer, a video camera, a goggle-type display, a digital camera
and a cellular phone.

54. (Previously Presented) A method of manufacturing a light-emitting device
according to claim 51, wherein the evaporation cell comprises a material selected from
the group consisting of boron nitride, alumina and tungsten.

55. (Previously Presented) A method of manufacturing a light-emitting device
according to claim 51, wherein the pattern of the light emitting layer has a width of about
50 to 200 μ m.

56. (Previously Presented) A method of manufacturing a light-emitting device
according to claim 1, wherein a diameter of the second portion is several tens to several
hundreds μ m.

57. (Previously Presented) A method of manufacturing a light-emitting device according to claim 3, wherein a diameter of the second portion is several tens to several hundreds μm .

58. (Previously Presented) A method of manufacturing a light-emitting device according to claim 21, wherein a diameter of the second portion is several tens to several hundreds μm .

59. (Previously Presented) A method of manufacturing a light-emitting device according to claim 51, wherein a diameter of the second portion is several tens to several hundreds μm .

60.-67. (Canceled)